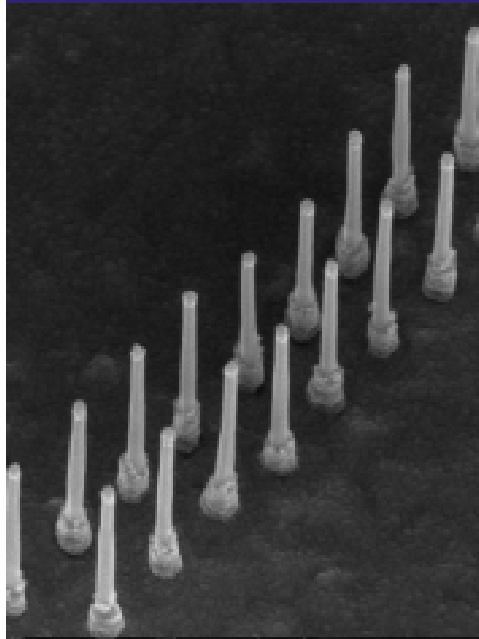


# Low Power III-V MOSFETs

Lars-Erik Wernersson

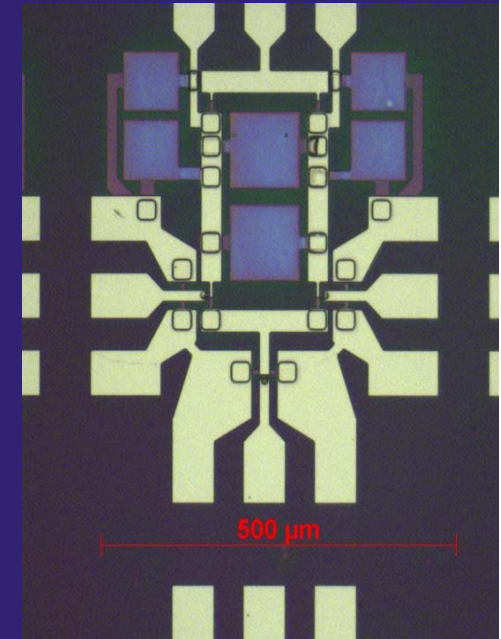
Electrical- and Information Technologies  
and Physics Department  
Lund University  
Sweden

## InAs Nanowires

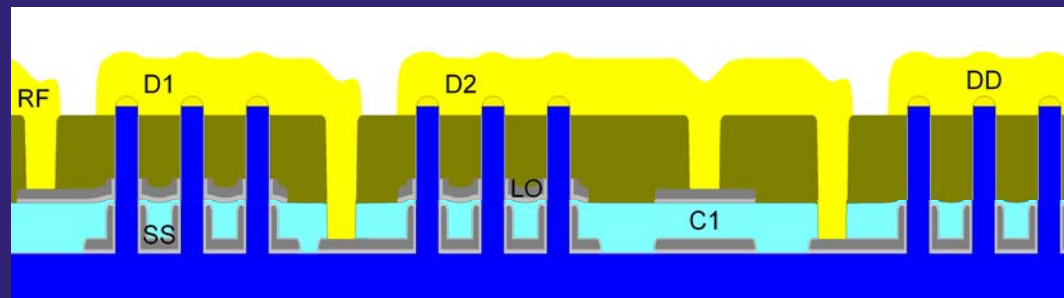


- High-speed digital and RF-circuits based on nanowire transistors
- Wrap-gates used to scale towards 10 nm  $L_g$
- Optimize materials and device concepts
- How much do we gain by increasing  $g_m$  at low drive voltages ( $V_{dd}=0.5$  V)?
- Can we reduce some “key capacitances” in the vertical geometry?

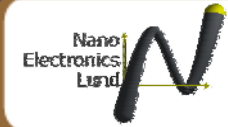
## Fabricated mixer



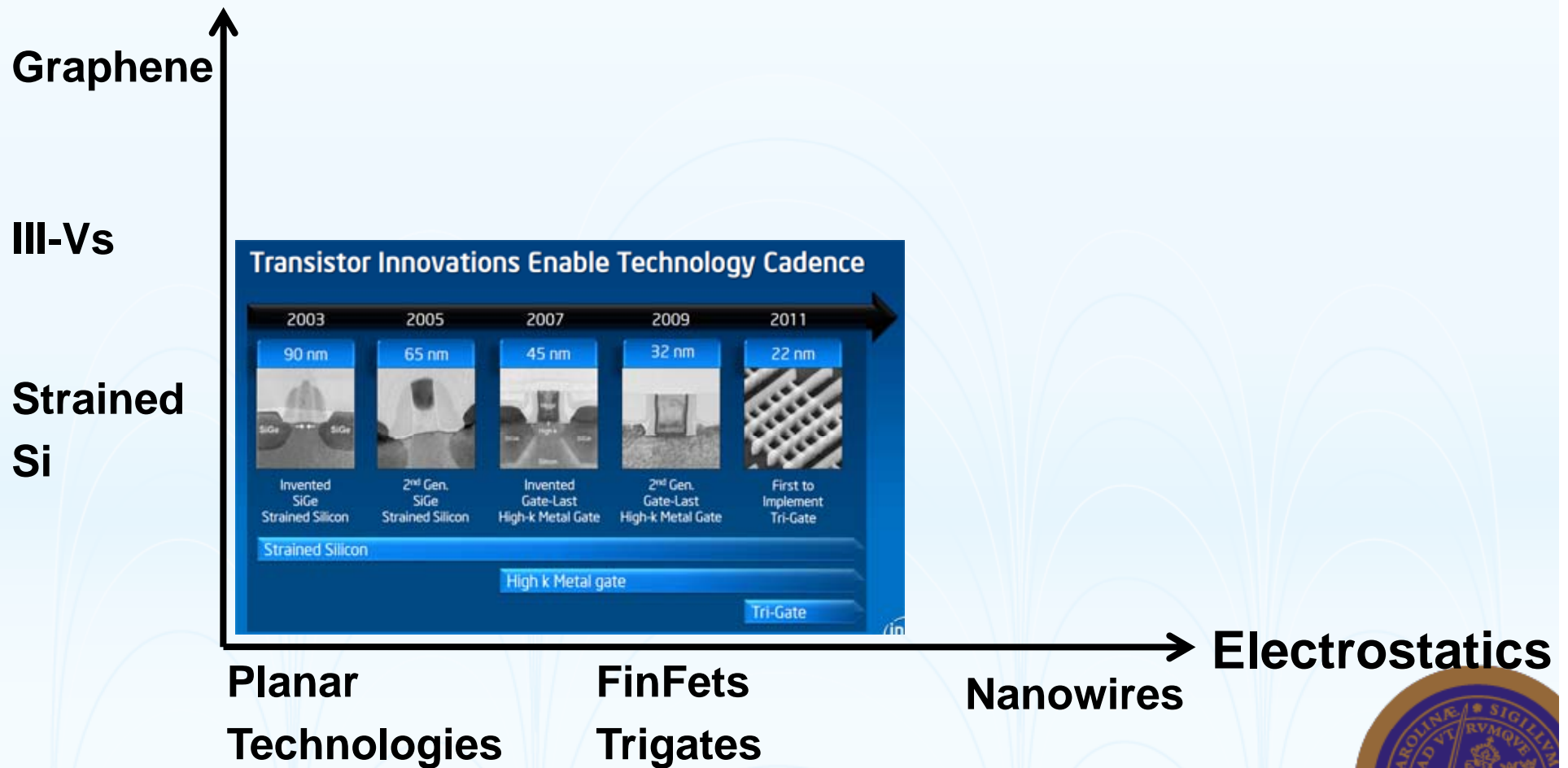
## Schematic cross-section



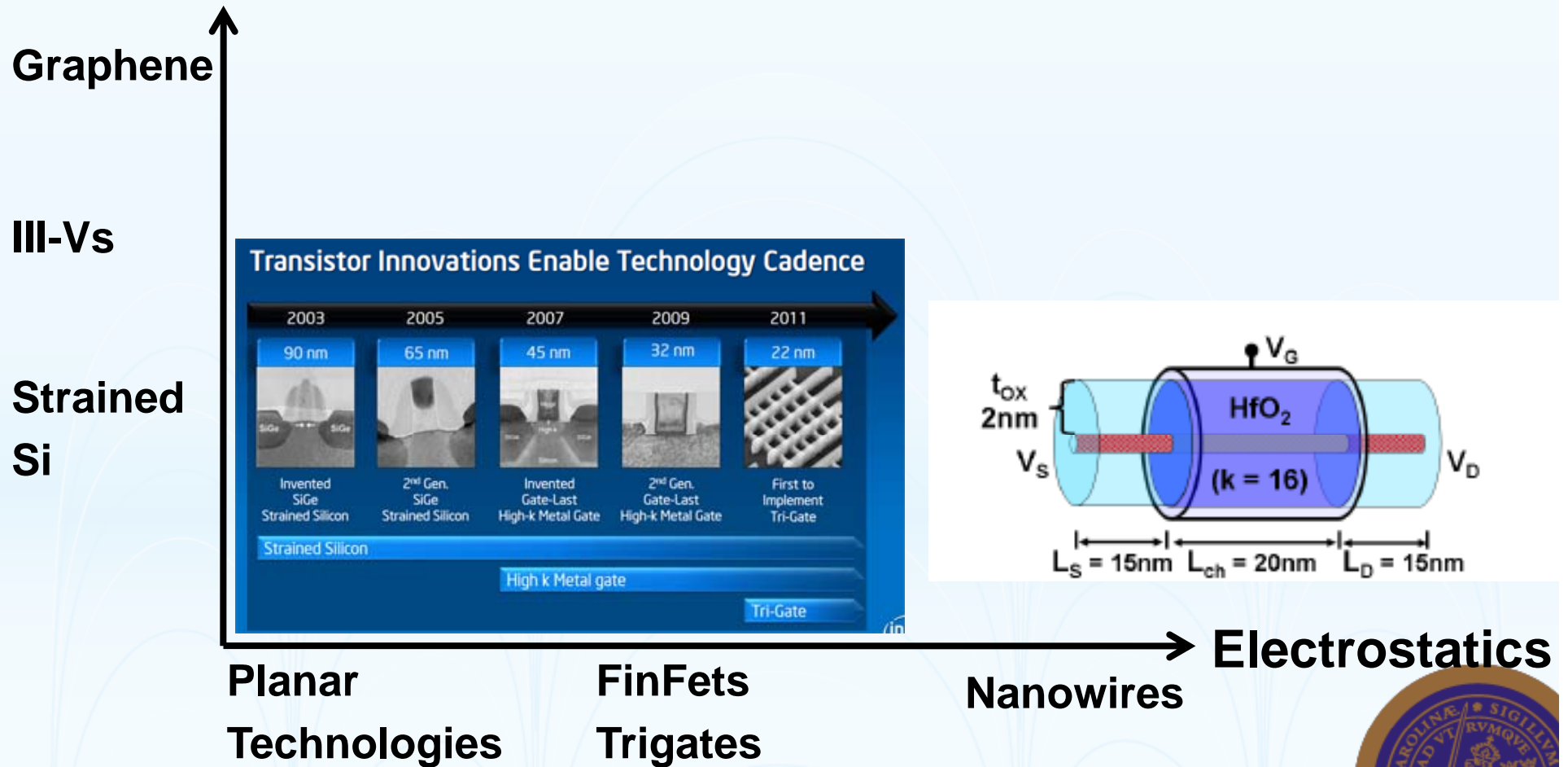
# Current Trends in Device Scaling



## Transport Enhancement



## Transport Enhancement



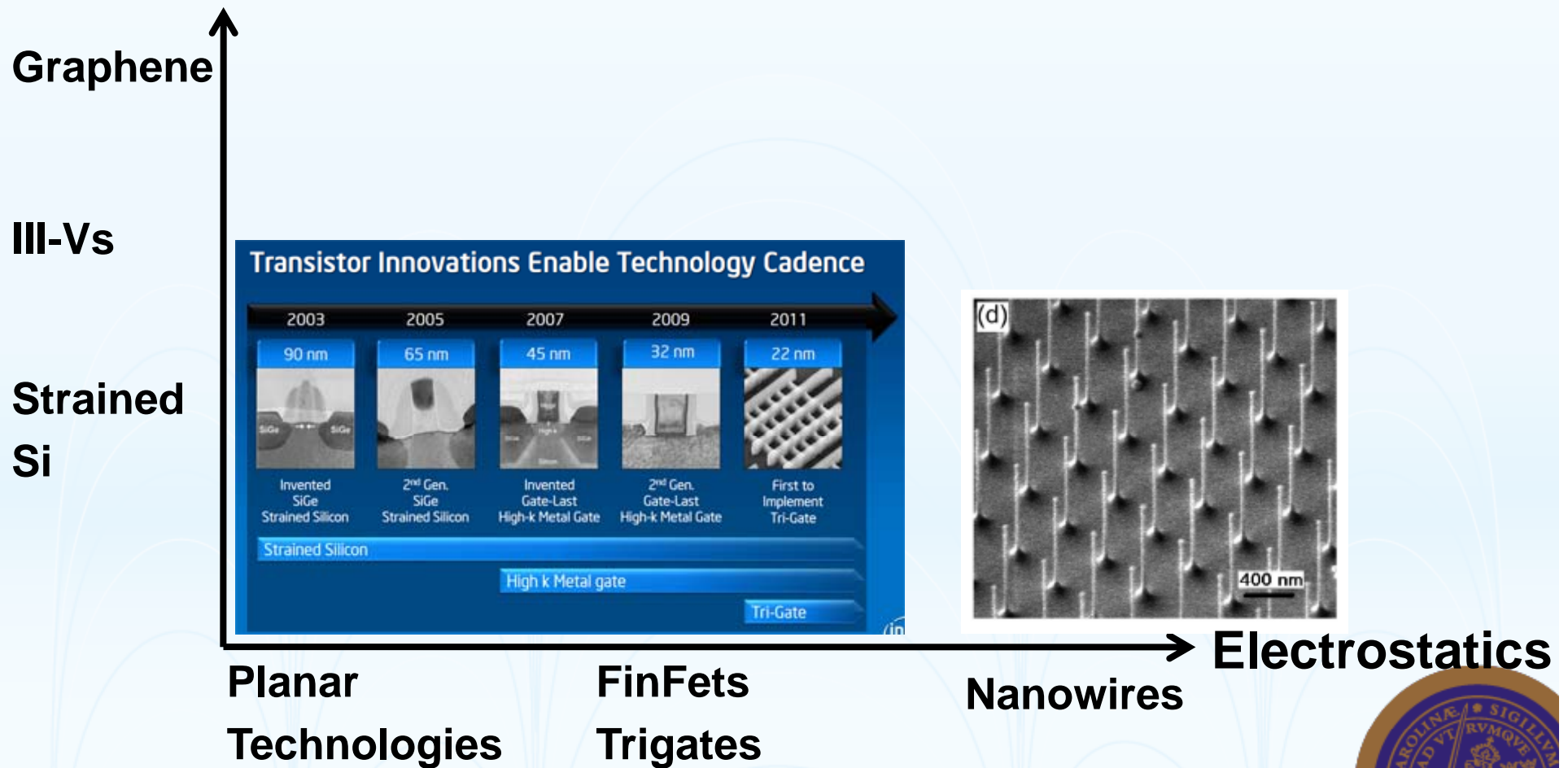
Planar Technologies

FinFets Trigates

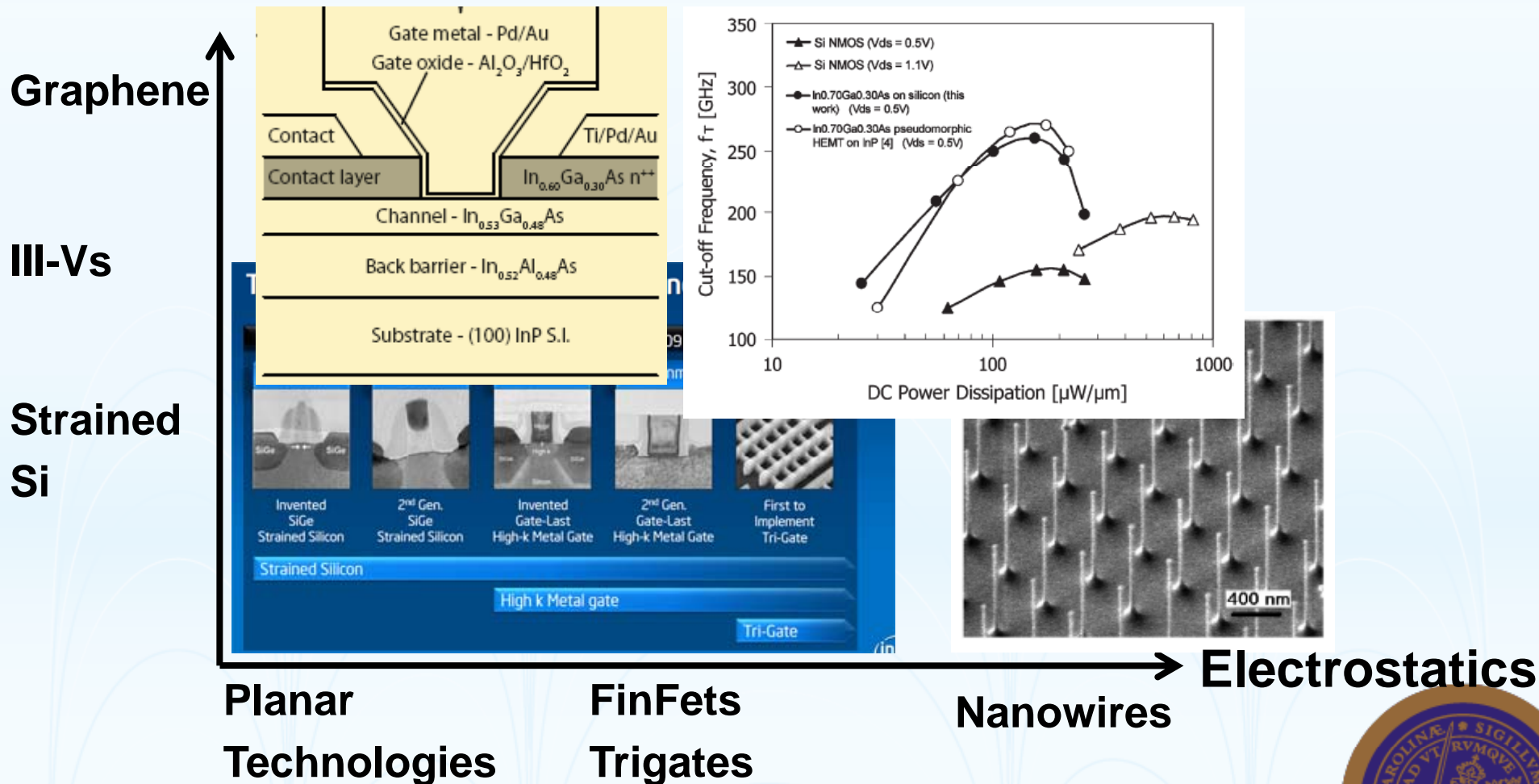
Nanowires



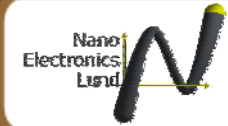
## Transport Enhancement



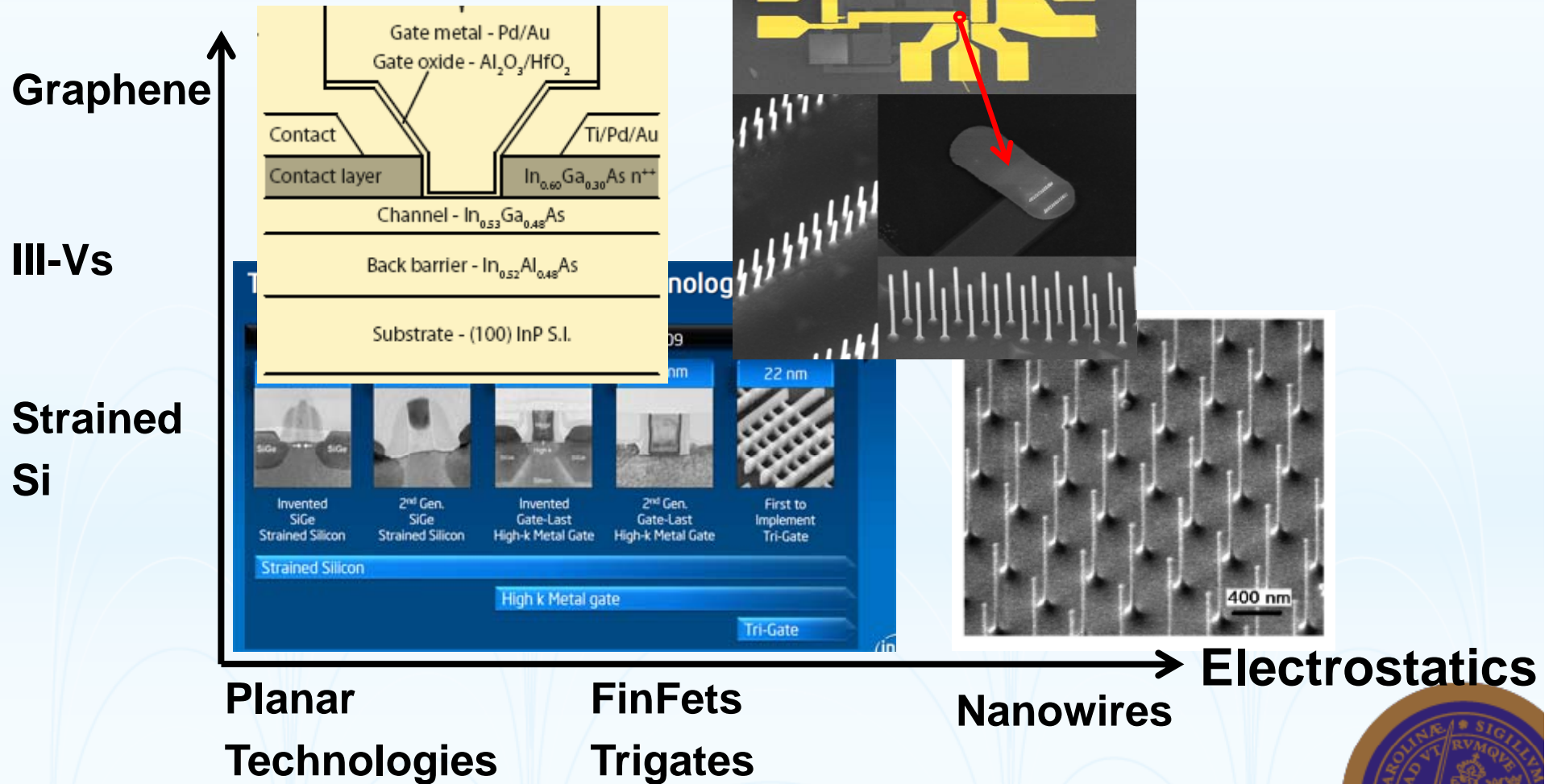
## Transport Enhancement



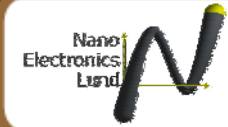
# Current Trends in Device Scaling



## Transport Enhancement



# Current Trends in Device Scaling

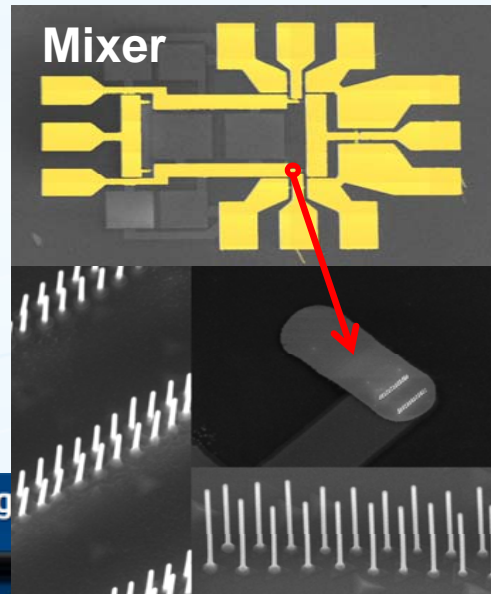
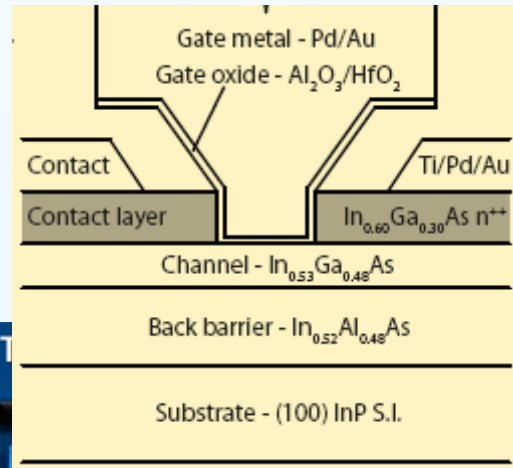


## Transport Enhancement

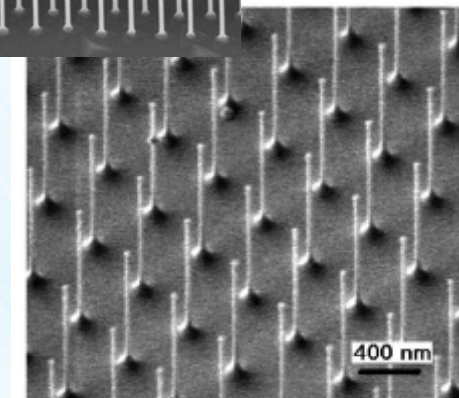
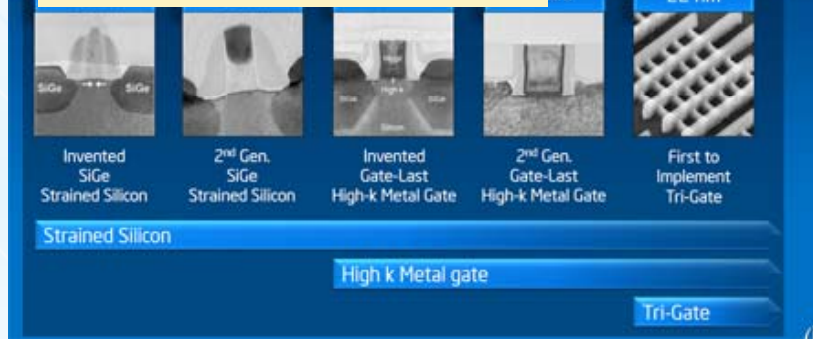
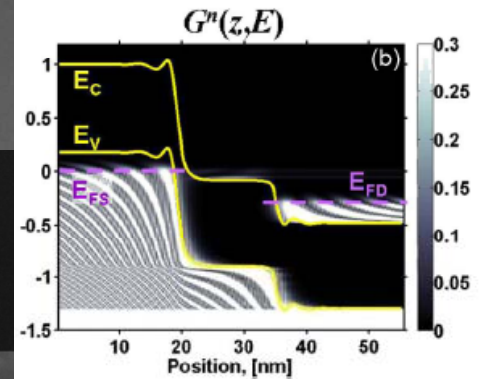
Graphene

III-Vs

Strained Si



## More than Moore Beyond Moore



Planar Technologies

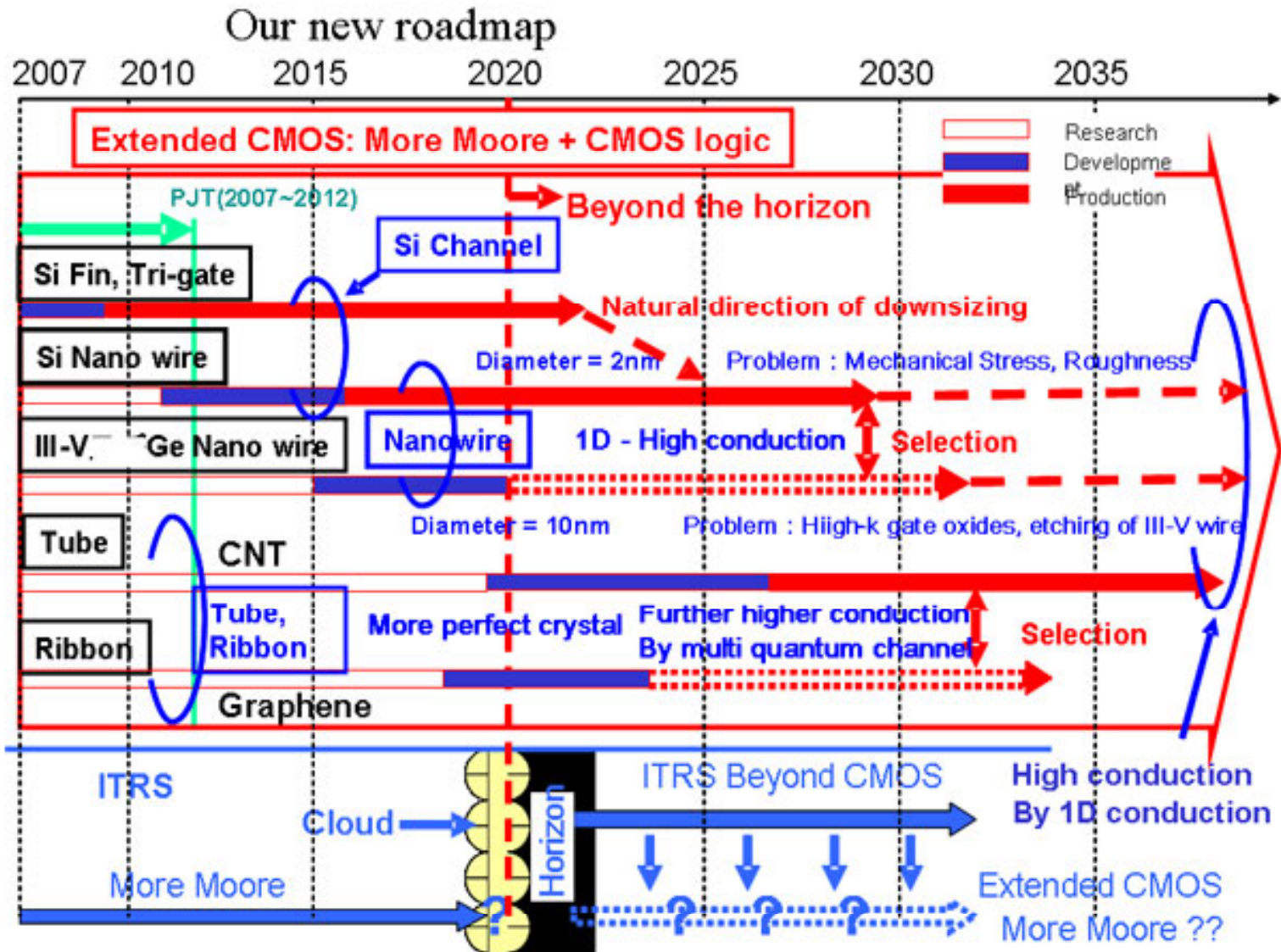
FinFets Trigates

Nanowires

Electrostatics







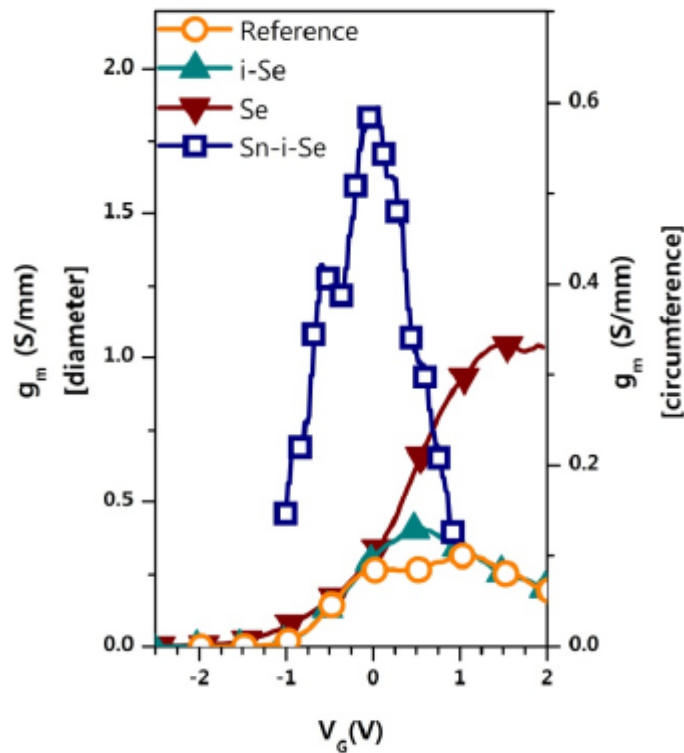
A roadmap from Japan's technical community sees silicon nanowires extending the reach of multi-gate devices.

H. Iwai (Tokyo Inst. of Techn.)

ISAGST, Sept. 25-28, 2007  
 Dallas, Texas, USA

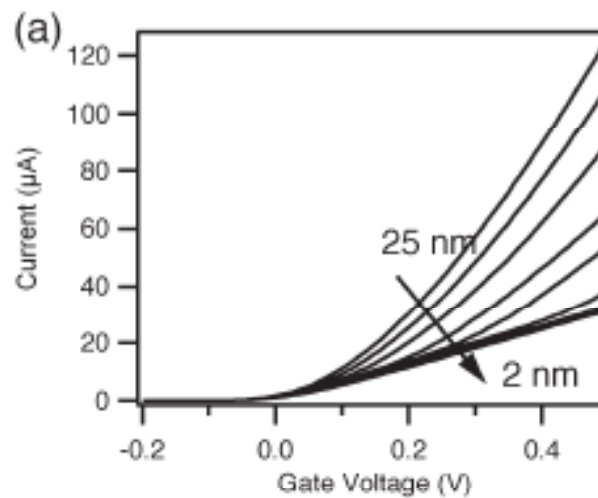


## Transport in thin (15 nm) InAs NWs



Lateral transistors 500 nm  $L_g$   
Doping essential to reduce access resistance

Max transconductance 1.8 S/mm  
 $I_d = 8300$  kA/cm<sup>2</sup> or 600 mA/mm  
Best  $g_m/g_o = 10.4$

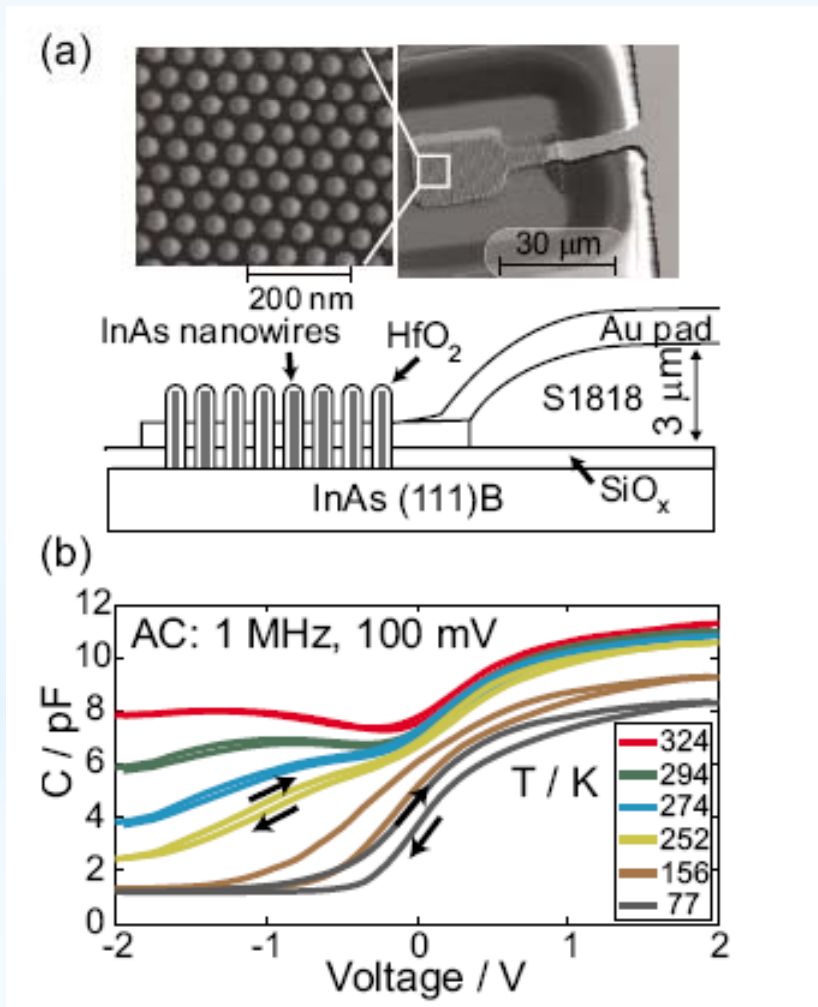


**Simulated data  
(tight binding)**

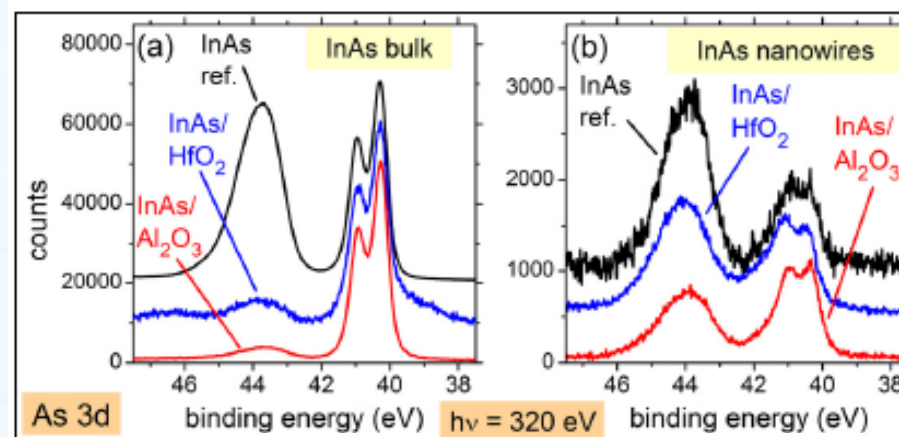
$I_{on} = 120$   $\mu$ A

$I_{on,exp} = 30$   $\mu$ A

## InAs/HfO<sub>2</sub> nanowire capacitors



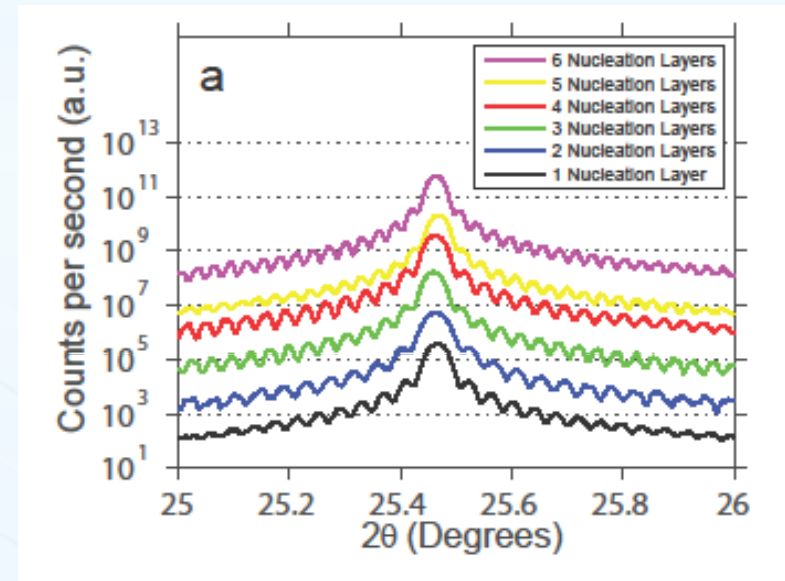
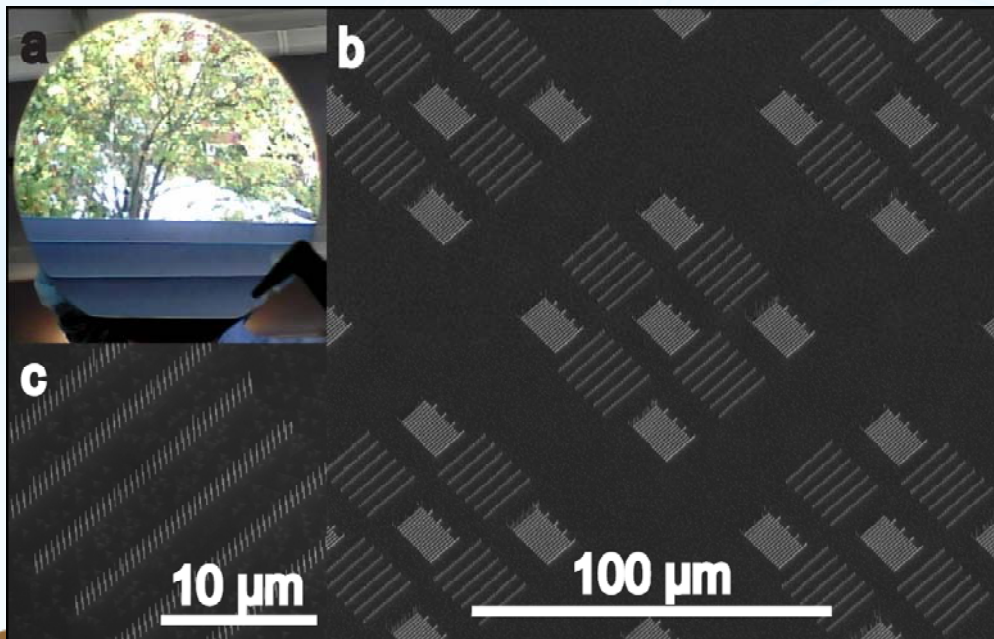
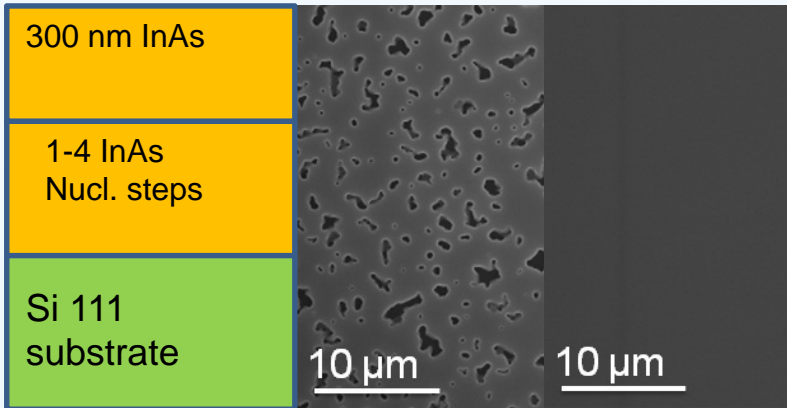
## XPS on InAs nanowires



Nanowire capacitors behave like planar InAs capacitors

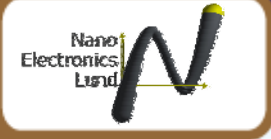
Temperature and frequency dependence  
 Holes may play a role due to narrow gap  
 Less effective oxide reduction

## Effect of InAs nucleation layer

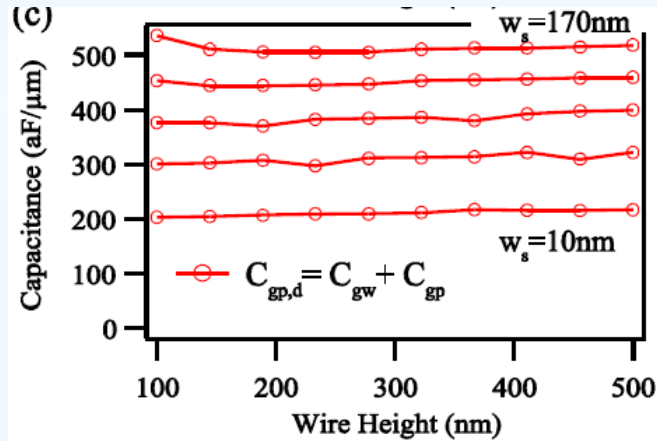
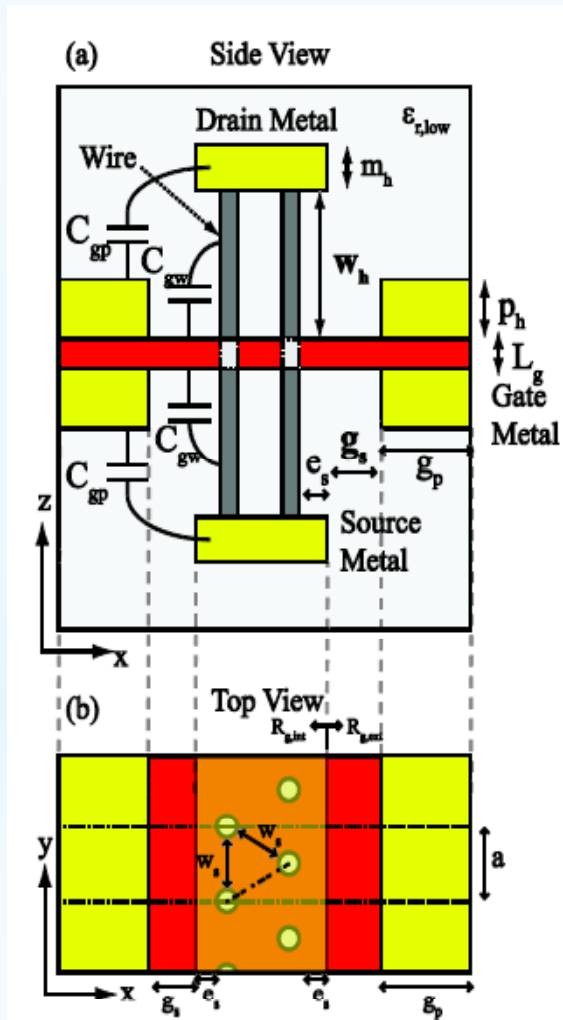


Buffer layer technology  
used for InAs layers on Si  
4-6 nucleation layers  
Wafer patterning  
Uniform nanowire growth

# Strategy to Reduce Capacitances



Close packing of nanowires to screen the electric fields



Internal capacitance low in the quantum limit, also including parasitics advantages are found

TABLE I  
BENCHMARKING OF PARASITIC CAPACITANCES

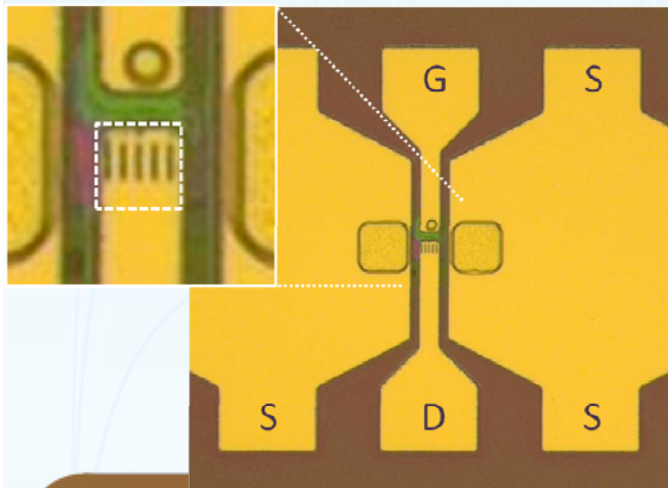
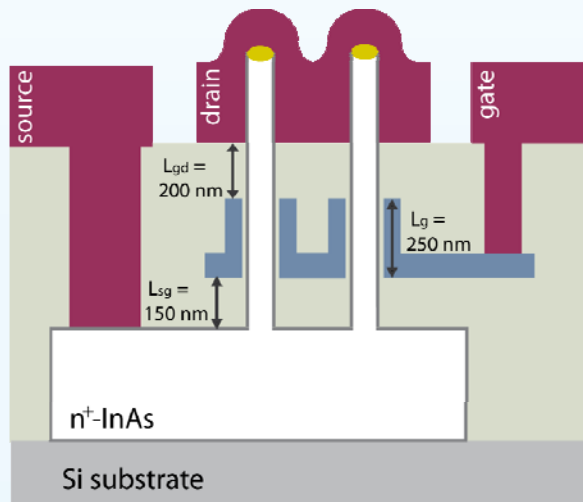
Node	$L_g$	$f_t$ -design		$f_{max}$ -design <sup>a</sup>		ITRS <sup>b</sup>	
		$C_{gg,i}$	$C_{gg,t}$	$C_{gg,i}$	$C_{gg,t}$	$C_{gg,i}$	$C_{gg,t}$
35 nm	47.1 nm	364	611	364	741	766	967
22 nm	29.6 nm	285	514	285	655	739	980
16 nm	21.5 nm	235	511	235	617	675	888
12 nm	16.1 nm	218	449	218	590	501	716
8 nm	11.1 nm	127	403	127	509	378	562

<sup>a</sup>  $f_{max}$ -optimized design with double gate electrode.

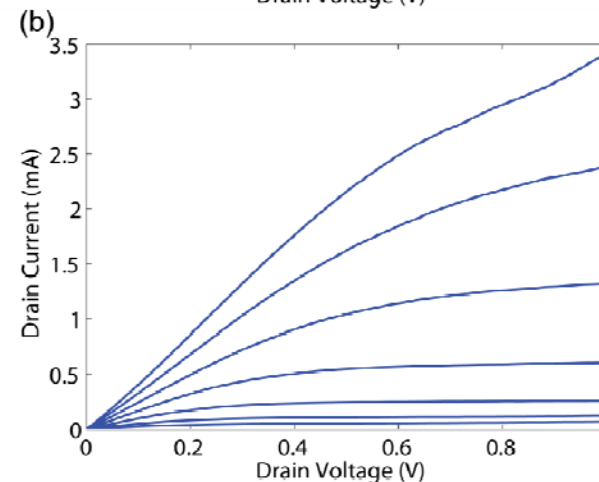
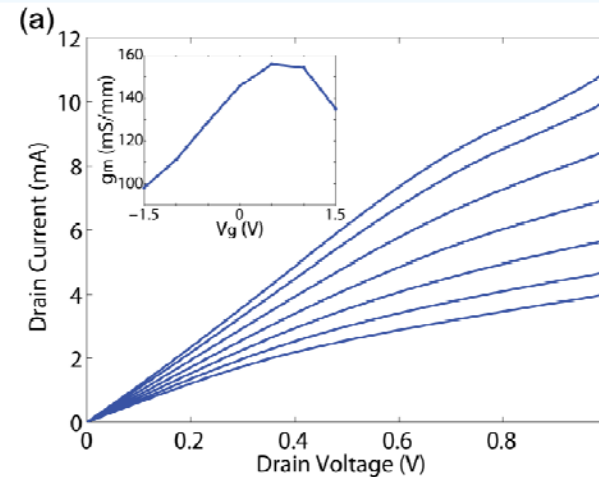
<sup>b</sup> Interpolated data from the ITRS roadmap.



## Device layout with W gate



182 nanowires, 35 nm diameter



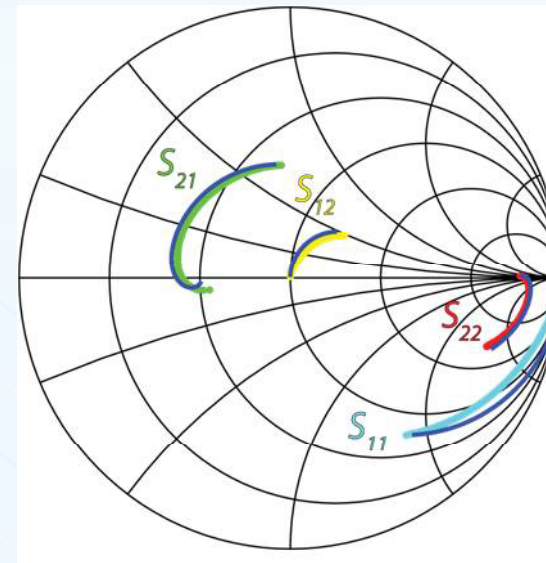
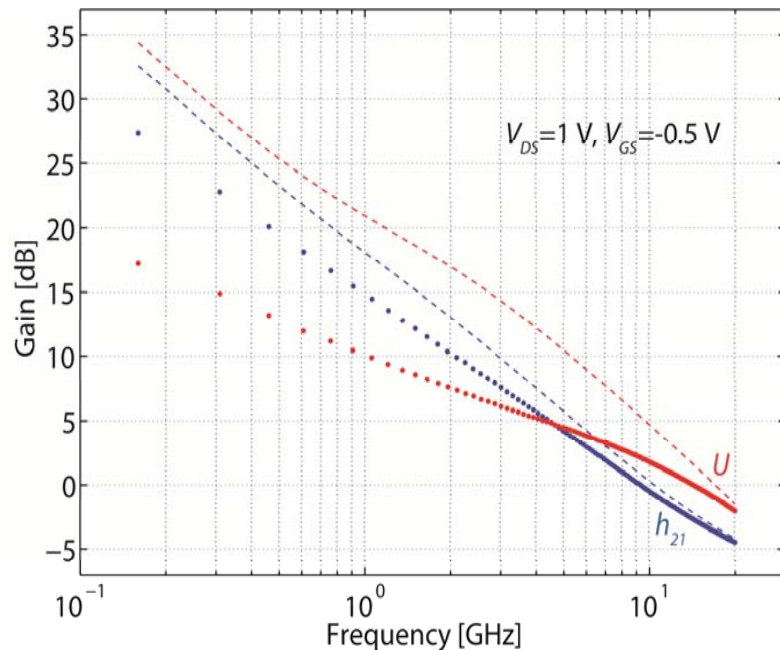
PMA 300 °C

30 min

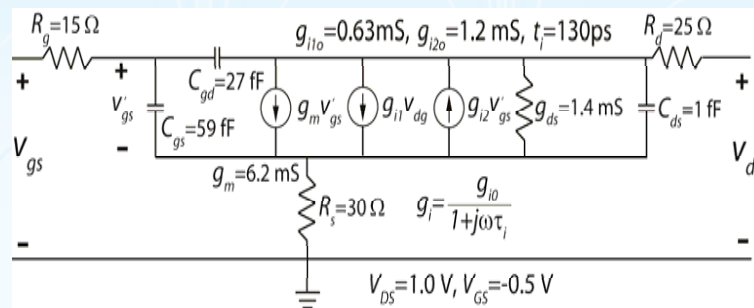
$I_{\max}$  550 mA/mm

As processed device

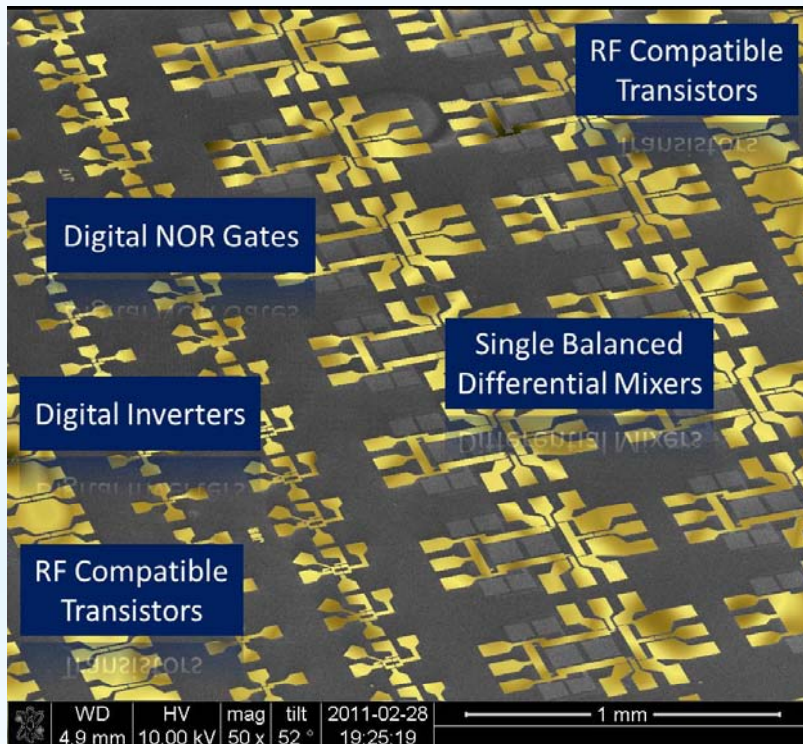
## Measured High-Frequency Properties



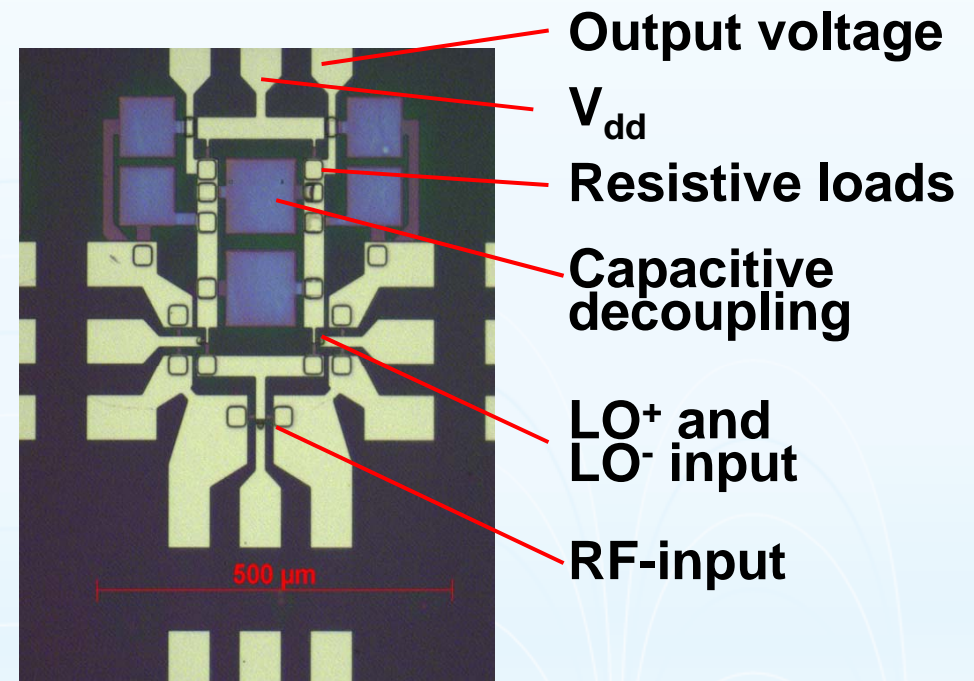
$f_t$  and  $f_{max}$  limited by parasitics  
 Intrinsic  $f_t$  about 200-300 GHz  
 Non-ideal U and S11: High- $\kappa$ ?



**Good wafers: 80% yield**  
**Area: 2000x6000  $\mu\text{m}^2$**



**First test circuit:**  
**Balanced mixer**

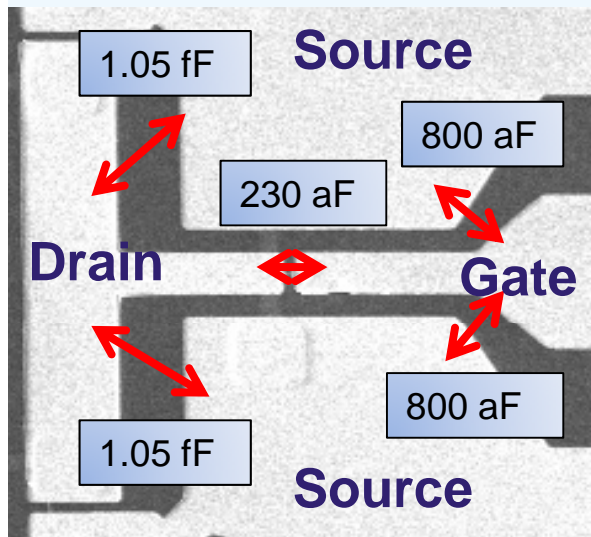


Design with 52 nanowire transistors  
Nanowire resistors  
Designed for 1 GHz input

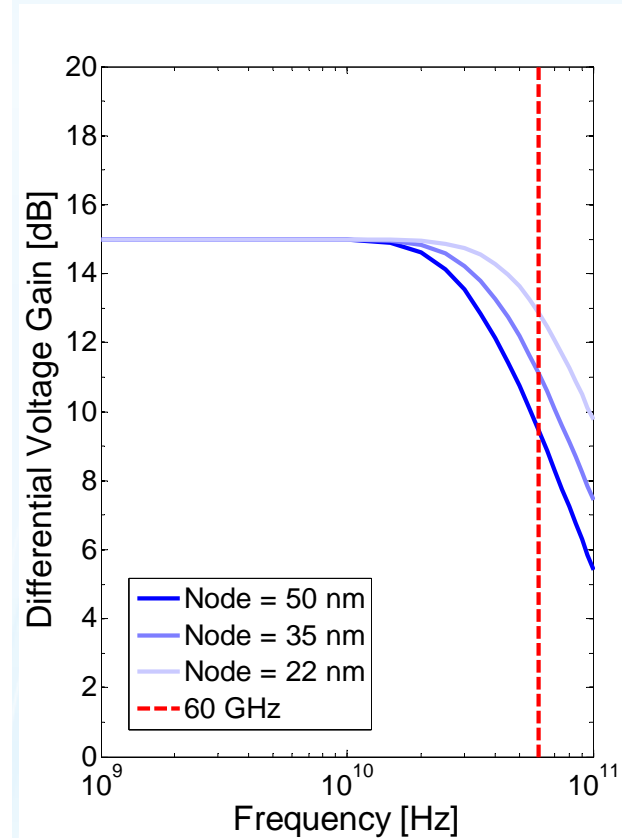
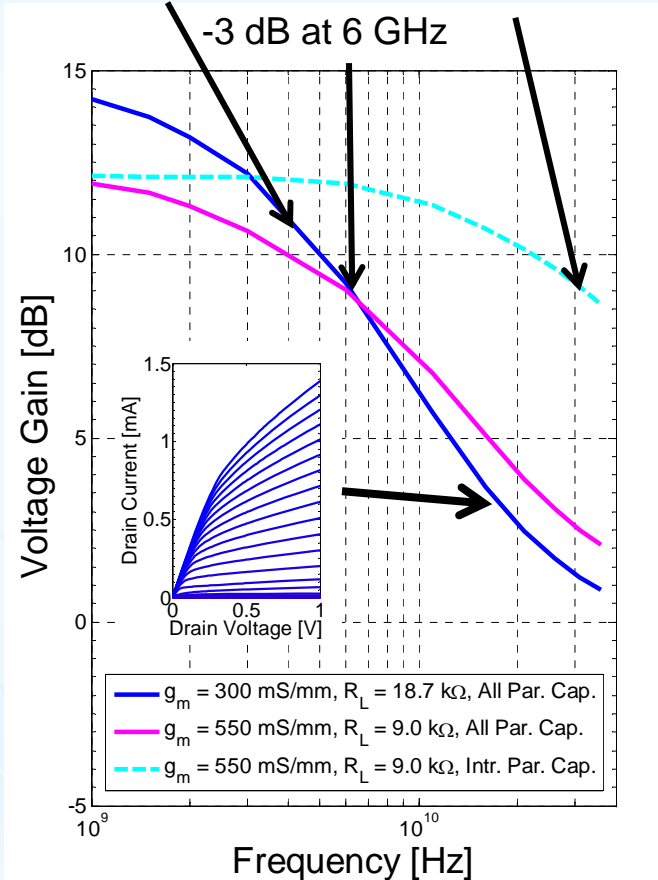


DC model from experimental data

Evaluation of parasitics



-3 dB at 4 GHz      -3 dB at 31 GHz  
-3 dB at 6 GHz



Par	Par	Par	Int	Int	Int
$C_{gs}$	$C_{gd}$	$C_{ds}$	$C_{gs}$	$C_{gd}$	$C_{ds}$
7.9 fF	6.5 fF	2.1 fF	1.6 fF	1.2 fF	0.7 fF

$V_{dd}=1V$

$V_t=0.1 V$

$g_m=300 \text{ mS/mm}$

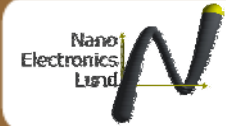
$V_{od}=80 \text{ mV}$

$I=51 \mu A$

$P=51 \mu W$



# Benchmarking III-V MOSFETs

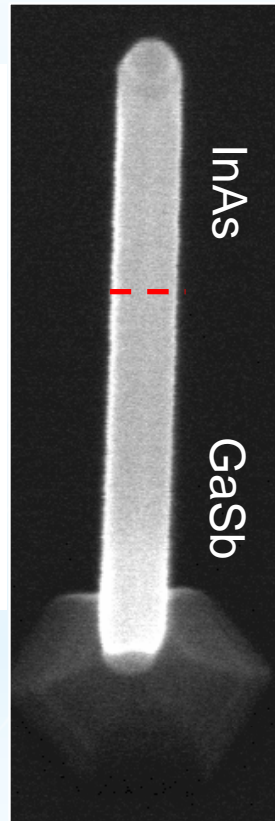
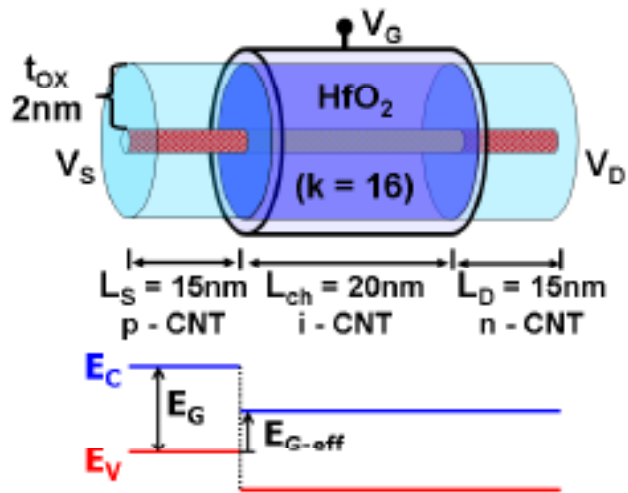


Technology	Drive current (mA/mm) $V_{ds}=0.5V$	Trans-conductance (mS/mm) $V_{ds}=0.5V$	$L_g$ (nm)	SS (mV/dec)
Lund DC NW Transistors 2008	330	520	50	88
Lund RF NW Transistors 2011	140	1000	250	-
Lund Planar Transistors 2011	2000	1900	55	187
Intel FinFETs 2010	100	500	70	120
Purdue FinFETs 2009	150	200	100	170
Intel Planar 2009	550	1750	75	100
UCSB Planar * 2009	950	450	200	550

\*  $V_{gs}=4$   $V_{ds}=2$

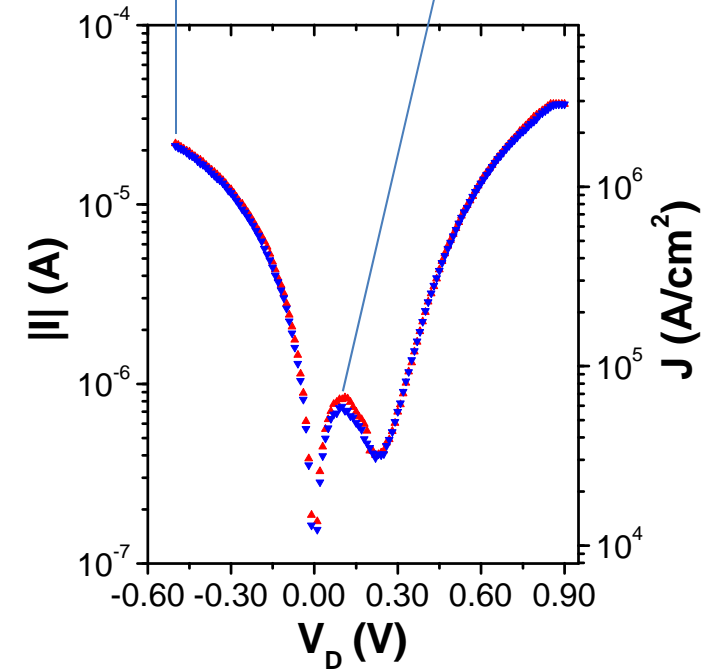


## InAs/GaSb Esaki diodes for TFETs



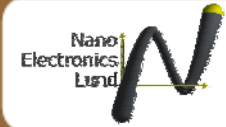
InAs growth at 460C

-22  $\mu\text{A}$  @ -0.50 V  
 (1750  $\text{kA}/\text{cm}^2$ )    838 nA @ 0.11 V  
 (66.7  $\text{kA}/\text{cm}^2$ )

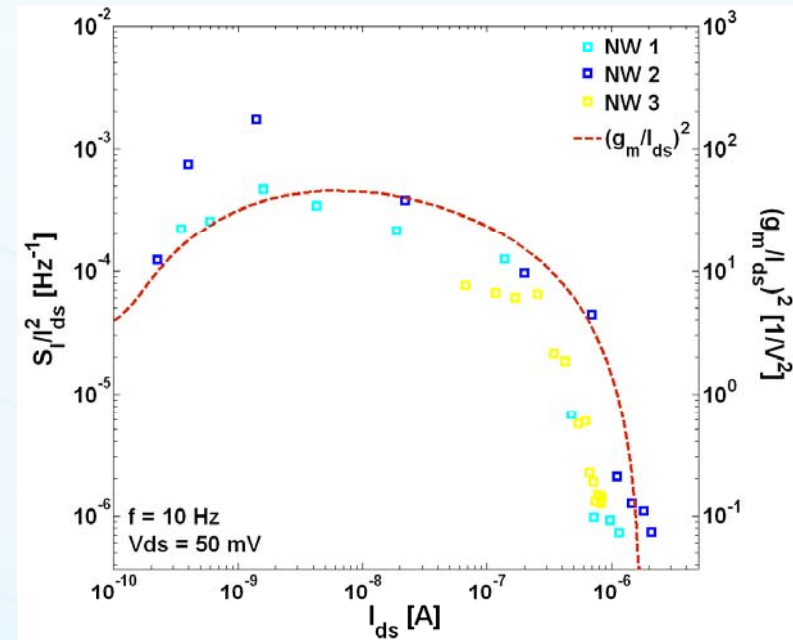
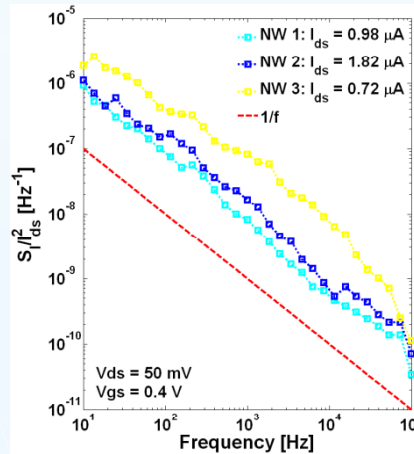
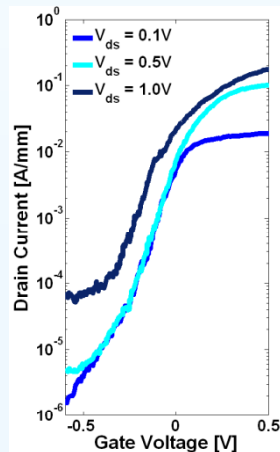
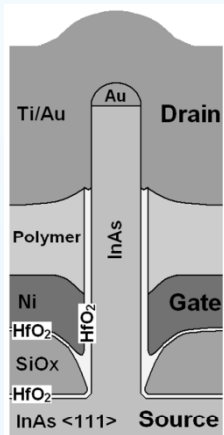


Diameter 40 nm  
 PVR @ RT = 2.1

# Low-Frequency Noise



## Cross-section DC-characteristics 1/f-noise



Average SS: **130 mV/decade**  
 Norm.  $I_{ds}$ : **0.16 S/mm**  
 $V_T$ : **-0.1 to 0.0 V**

$$\frac{S_I}{I_{DS}^2} = \left( \frac{q^2 k T \lambda N}{f \gamma W L C_{ox}^2} \right) \frac{g_m^2}{I_{DS}^2}$$

Hooge's Parameter:  **$4.2 \times 10^{-3}$**

Normalized 1/f Noise Figure:  **$7.3 \times 10^{-7} \text{ Hz}^{-1}$**  *Persson et al IEEE EDL, 31, 428 (2010)*

Indication of number fluctuations.

Traps are equally distributed in energy.

Noise figure is comparable with other studies on NW FETs

The Hooge's parameter has a relatively low value.



## 23 Journal Papers 2010-2011

1 Invited in Proceedings of IEEE

2 IEEE Trans Microwave Theory and Techniques

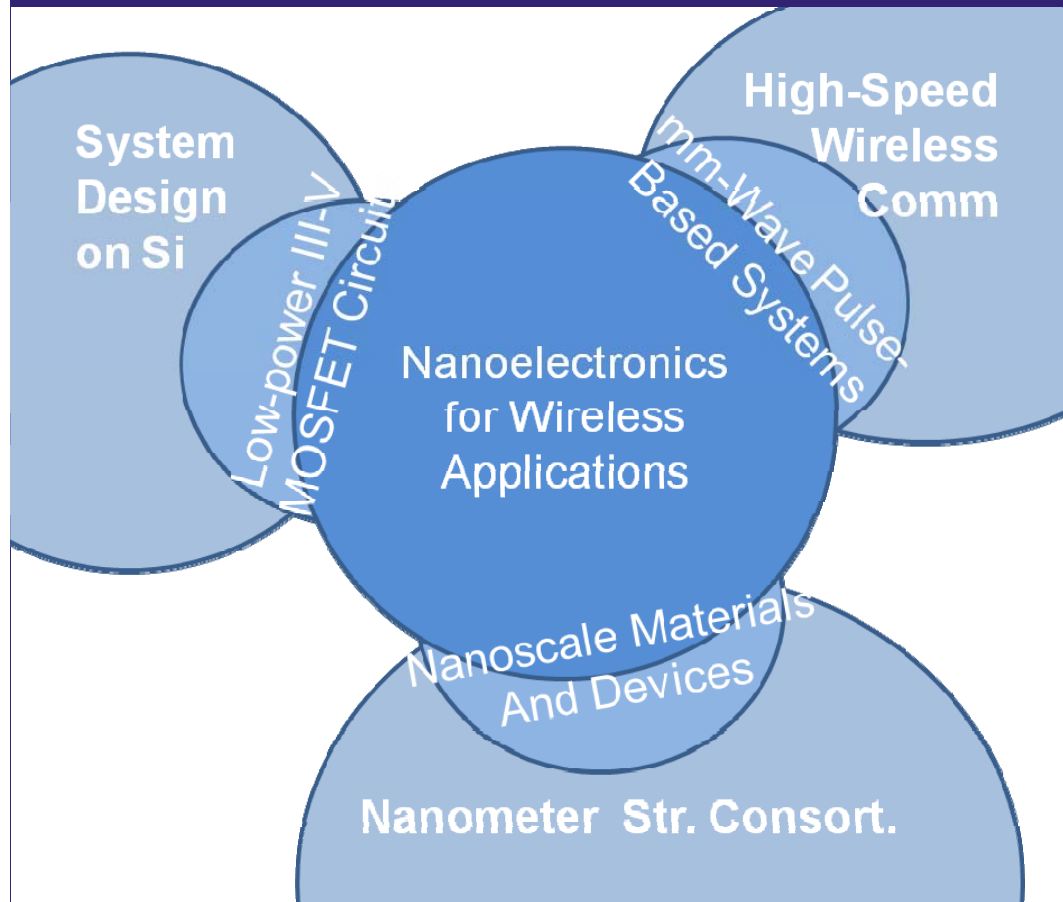
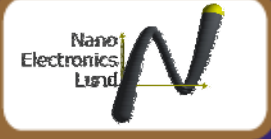
2 IEEE EDLs/Electronics Letters

1 IEEE MWCL

7 APLs/NanoLetters

3 patent applications filed

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Lars Ohlsson



VINNOVA

